

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Attorney Docket Number	4641-61273
Application Number	10/000,458
Filing Date	November 30, 2001
First Named Inventor	Yahiro
Art Unit	2881
Examiner Name	Mary A. El Shammaa

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
UM.E.		6,059,981	9-May-2000	Nakasuji
UM.E.		5,396,077	7-Mar-1995	Sohda et al.

FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
UM.E.		P2001-203149A	27-Jul-2001	Japan

OTHER DOCUMENTS

UM.E.	"New imaging and deflection concept for probe-forming microfabrication systems", by H.C. Pfeiffer, J. Vac. Sci. Technol., Vol 12, No. 8, Nov./Dec. 1975, pages 1170-1173

EXAMINER SIGNATURE: <i>UM.El Shammaa</i>	DATE CONSIDERED: <i>11.12.03</i>
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	